



First-Principles Study for ALD of MoS₂



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1. Introduction/Background

Atomic layer deposition (ALD)

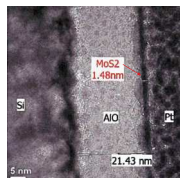
- ALD is a method for thin-film deposition with atomic precision.
- Volatile gas phase precursors allow lower reaction temperatures.
- Precursors are introduced sequentially and are self-limiting.

Molybdenum disulfide (MoS₂)

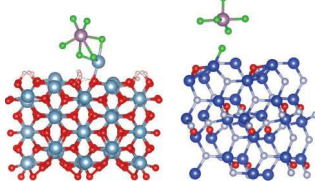
- 2D-MoS₂ is a semiconductor with a direct band gap of 1.8 eV [2].
- Applications in microelectronics, photovoltaics, and batteries [2].
- Deposited via ALD with molybdenum hexafluoride (MoF₆) and hydrogen sulfide (H₂S) precursors [1].

Challenges with ALD of MoS₂

- Difficult to study *in situ*.
- Relatively new and unknown chemistry.
- MoF₆-substrate interactions are unknown.



Above: Transmission electron microscope images of MoS₂ deposited on Al₂O₃ by ALD [1]. Below: Model of a single MoF₆ on hydroxylated Al₂O₃ (left) and Si₃N₄O (right) surfaces.



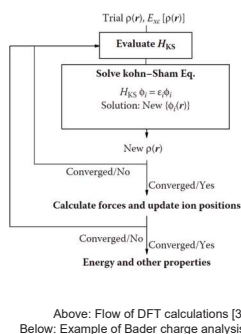
2. Project Goals and Methods

Project Goals

- Understand *role of hydroxyl groups* (OH) on Al₂O₃, Si₃N₄O, and TiO₂ substrates with a *single MoF₆ precursor*.
- Explain *bonding and reduction* mechanisms during first MoF₆ half-cycle.

Density functional theory (DFT)

- DFT is a first-principles computational modeling method (based on quantum mechanics rather than classical mechanics or empirical data).
- Calculates ground-state properties of a system.
- Less than 1,000 atoms in DFT modeled systems [3].
- We used the Vienna Ab initio Simulation Package (VASP) to implement DFT [4].



Above: Flow of DFT calculations [3]. Below: Example of Bader charge analysis.

Bader charge analysis

- Bader charge analysis creates Bader volumes from "zero-flux surfaces" around each atom [5].
- Using VASP output, it can determine the valence electron density within each Bader volume.
- Quantifies donation or acceptance of electron density for each atom in a system.

Atom #	Initial valence electrons	Bader charge	Δ valence electrons
Al11	3	0.56	-2.44

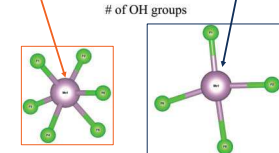
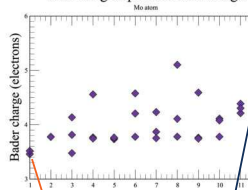
3. Results

Bader charge analysis of MoF₆ on hydroxylated Al₂O₃

- A single MoF₆ was placed on Al₂O₃ surfaces at varying hydroxyl concentrations.

Observation:
OH groups increase the Mo atom's local electron density indirectly.

of OH groups vs. Bader charge



MoF₆ on Al₂O₃ with 1 OH group: minimal electron localization (small Bader charge) corresponds to +6 oxidation state. MoF₆, 12 OHs: Large Bader charge corresponds to +4 oxidation state.

- A change in the oxidation state of Mo from +6 to +5, +4, and +3 is evident by increased local electron density [6].

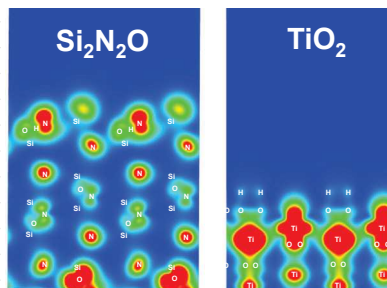
Legend

Mo	F	Al	O	H	N	Si
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Si₃N₄O and TiO₂ surface models

Substrate	Surface Energy (eV/Å)
TiO ₂ (100)	0.0237
TiO ₂ (110)	0.0433
TiO ₂ (111)	0.0596
Si ₃ N ₄ O (100)	0.1972
Si ₃ N ₄ O (110)	0.2815
Si ₃ N ₄ O (111)	0.1181

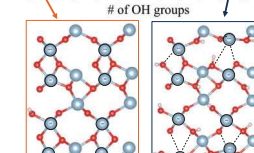
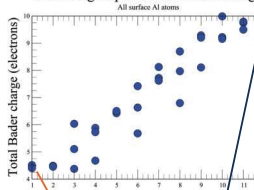
Surface formation energies of non-hydroxylated TiO₂ and Si₃N₄O surfaces cleaved from bulk at various Miller indices: (100), (110), and (111).



Partial charge densities of Si₃N₄O 110 (left) and TiO₂ 110 (right) surfaces, fully hydroxylated.

How?
OH groups break Al-O bonds.

of OH groups vs. total Bader charge



Top-down view of Al₂O₃ surface with 1 OH. Surface Al atoms outlined. MoF₆ omitted for clarity. Same surface with 12 OH. Dashed lines represent Al-O bonds broken by OH.

- This frees up Al electrons so they can form Al-F bonds.
- Results in separation of F atoms from MoF₆.
- Electrons from broken Mo-F bonds then localize to the Mo atom.

4. Analysis

MoF₆ on hydroxylated Al₂O₃

- Reducing Mo to an oxidation state of +4 may increase reaction favorability.
- We predict that the oxidation state of Mo in the product, MoS₂, is +4.
- However, the oxidation state of Mo in MoF₆ is +6.
- Similar molybdenum sulfide reactions are proposed to be most energetically favorable when Mo does not change oxidation state during the reaction [1].
- Mo-O bonds were not observed on OH groups, so more OH → fewer Mo-O bonds.
- Mo-O bonds are known to form in experiment [1].
- Minimizing these bonds could make the film/substrate boundary cleaner.

Si₃N₄O and TiO₂ substrates

- On (110) and (111) Si₃N₄O, hydroxylation increases partial charge density of O atoms.
- However, on (100) Si₃N₄O, hydroxylation decreases O atom partial charge density.
- Investigation of TiO₂ surfaces' partial charge densities is in progress.
- Initial results show that hydroxylation affect these partial charge densities as well.

5. Conclusions/Future Work

Conclusions

- Based on our analysis, we predict increased reaction favorability and cleaner film/oxide interfaces by maximizing OH concentration because:
 - OH groups break Al-O bonds on the Al₂O₃ surface and reduce the oxidation state of a deposited Mo atom.
 - OH groups hinder Mo-O interactions.
- Hydroxylation changes Si₃N₄O and TiO₂ surface O chemistry in different ways depending on the surface: (100), (110), or (111).

Future work

- Determine if surface decomposition of Al₂O₃ has any effects on material properties.
- Bader charge analysis of two or more MoF₆ molecules on Al₂O₃.
 - Preliminary results indicate that surface chemistry may vary with more MoF₆.
- Add H₂S to various MoF_x species and calculate reaction energy.
 - This will provide insight on the relation between oxidation states and reaction energy.
- Simulate ALD of MoS₂ on Si₃N₄O and TiO₂ surfaces.
 - Investigate the mechanism by which hydroxylation increases O partial charge on some structures but decreases it on others.

6. Acknowledgements

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